IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Confirmation No. 4423

omohiro OKUMURA et al.

Docket No. 2001-1089A

erial No. 09/918,823

Group Art Unit 2821

Filed August 1, 2001

Examiner T. Phan

PLASMA PROCESSING METHOD AND APPARATUS THEREOF

THE COMMISSIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT

ACCOUNT NO. 23-0975

REQUEST FOR RECONSIDERATION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action of May 21, 2003, a three month Extension of Time having been obtained, please consider the following remarks.

ECHNOLUGY CENTER 2800